

Notice of References Cited	Application/Control No. 10/075,602	Applicant(s)/Patent Under Reexamination HUNG ET AL.	
	Examiner Lynette T. Umez-Eronini	Art Unit 1765	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-4208241	06-1980	Harshbarger et al.	216/67
	B	US-4214946	07-1980	Forget et al.	438/712
	C	US-4713141	12-1987	Tsang	438/714
	D	US-5167760	12-1992	Mu et al.	438/714
	E	US-5202291	04-1993	Charvat et al.	438/696
	F	US-6004884	12-1999	Abraham	438/714
	G	US-5573679	11-1996	Mitchell et al.	216/2
	H	US-5549784	08-1996	Carmody et al.	438/700
	I	US-5269879	12-1993	Rhoades et al.	156/643
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Abraham et al., Methods and Apparatus for Etching Semiconductor Wafers, August 21, 1997, PCT WO 97/30472, pp. 1-23.
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.